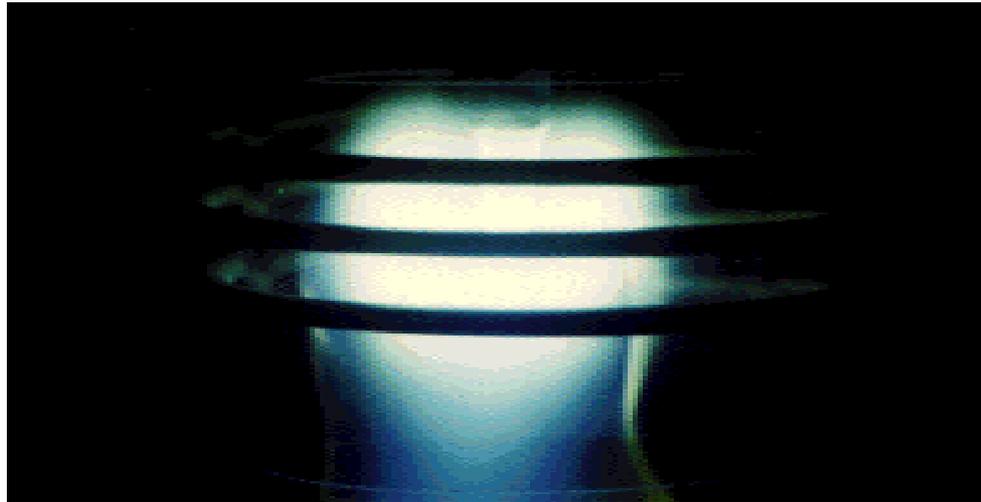


# RF Inductive Discharges



**EE 403/503**  
**Introduction to Plasma Processing**  
November 2, 2011

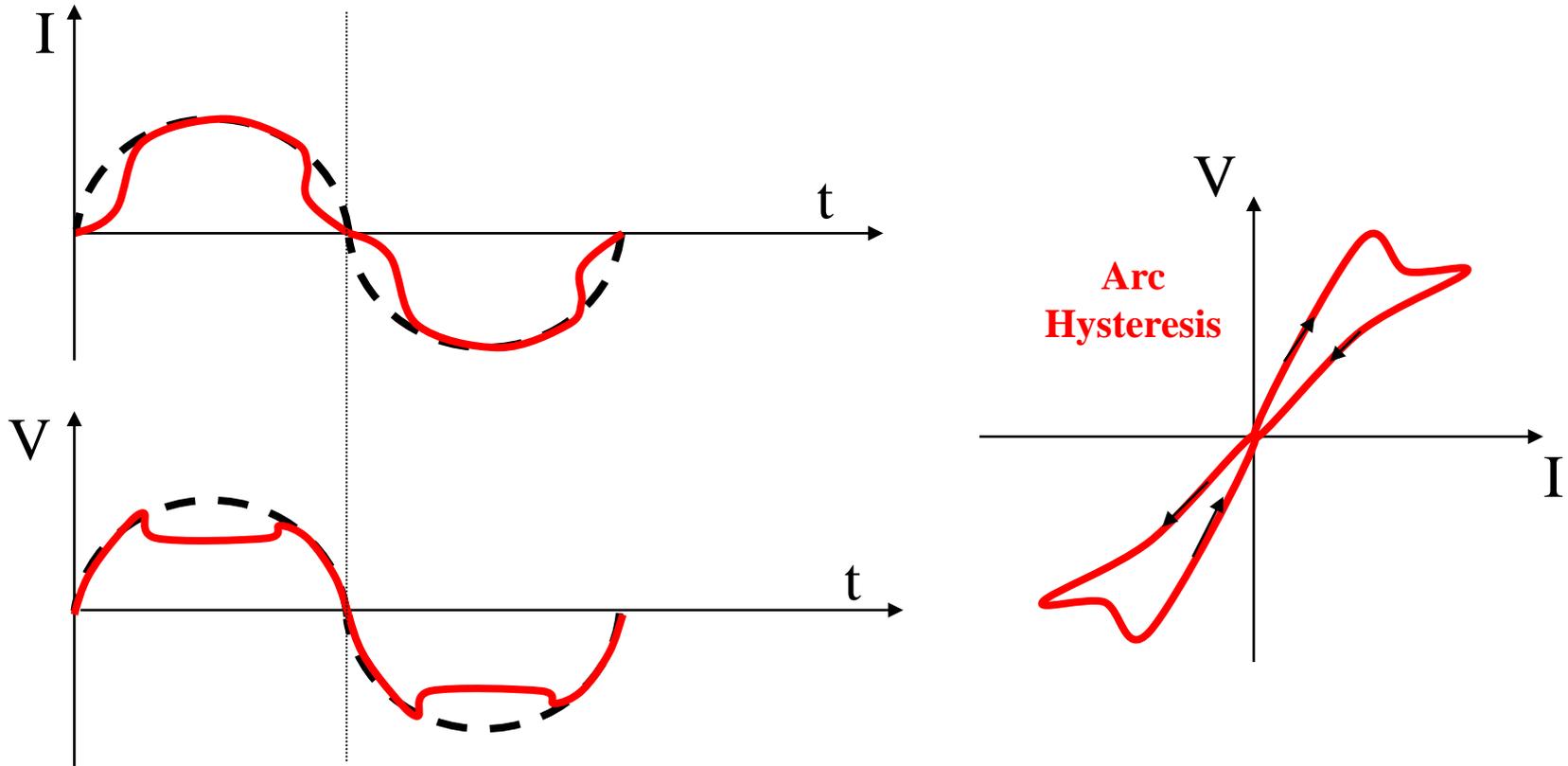
# Outline

1- RF Inductive Discharge

2- RF Capacitive Discharge

3- MW Discharge (quasi-optical)

# AC Arc

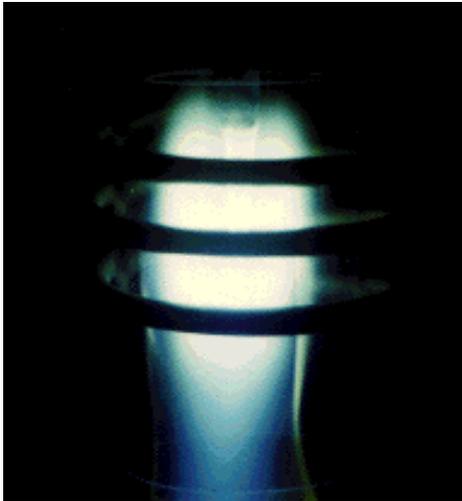


The arc extinguishes at  $V=0$  but the remaining ions reignite the arc at relatively low breakdown voltage.

Very high frequency eliminate the arc hysteresis.

# RF Discharges

(10 KHz-30MHz)



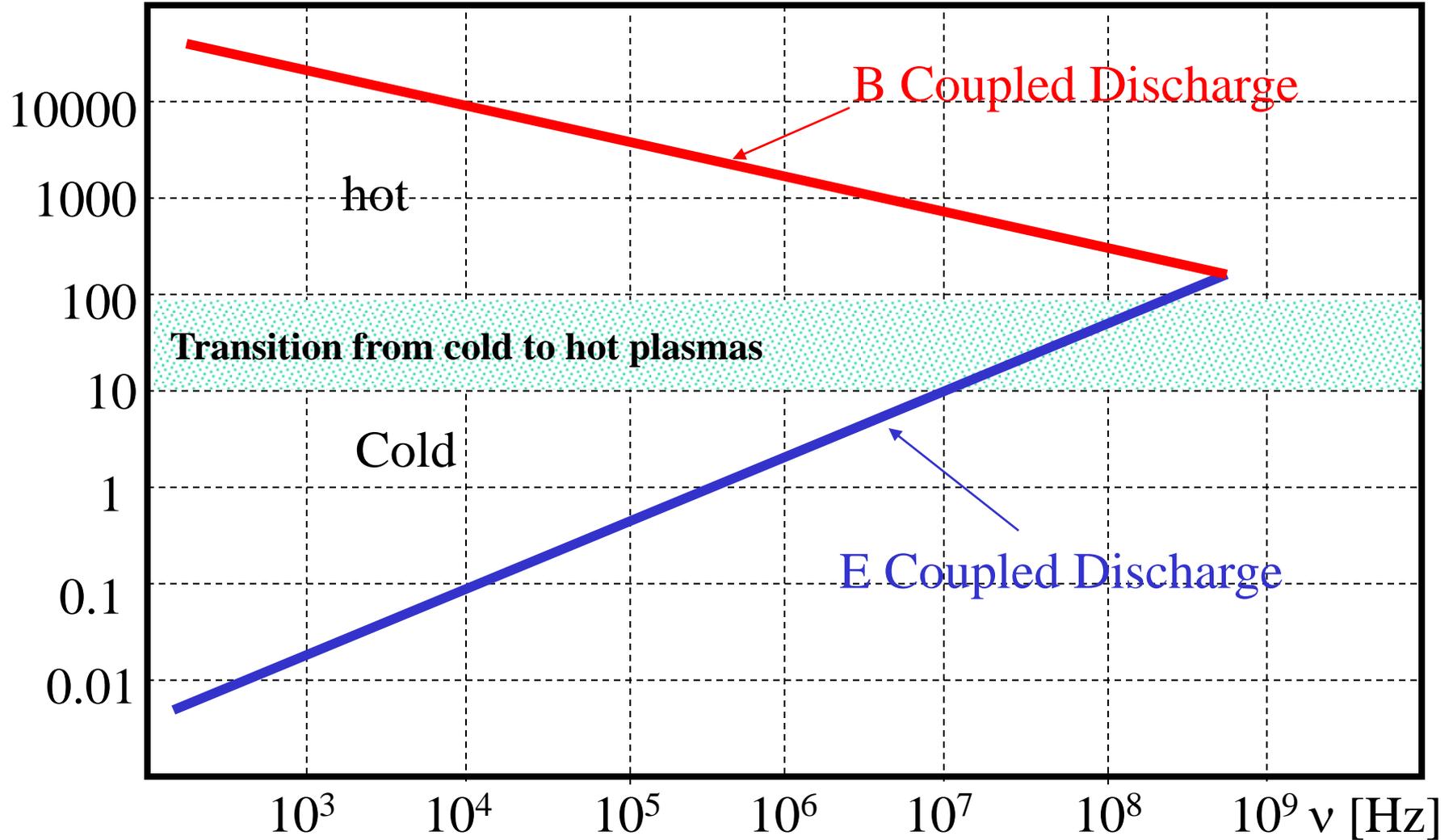
**Inductive Coupling**



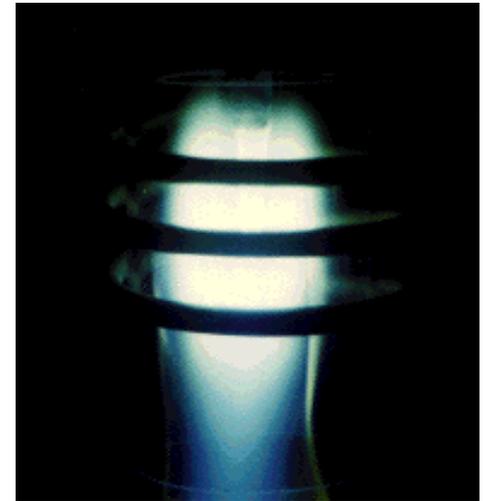
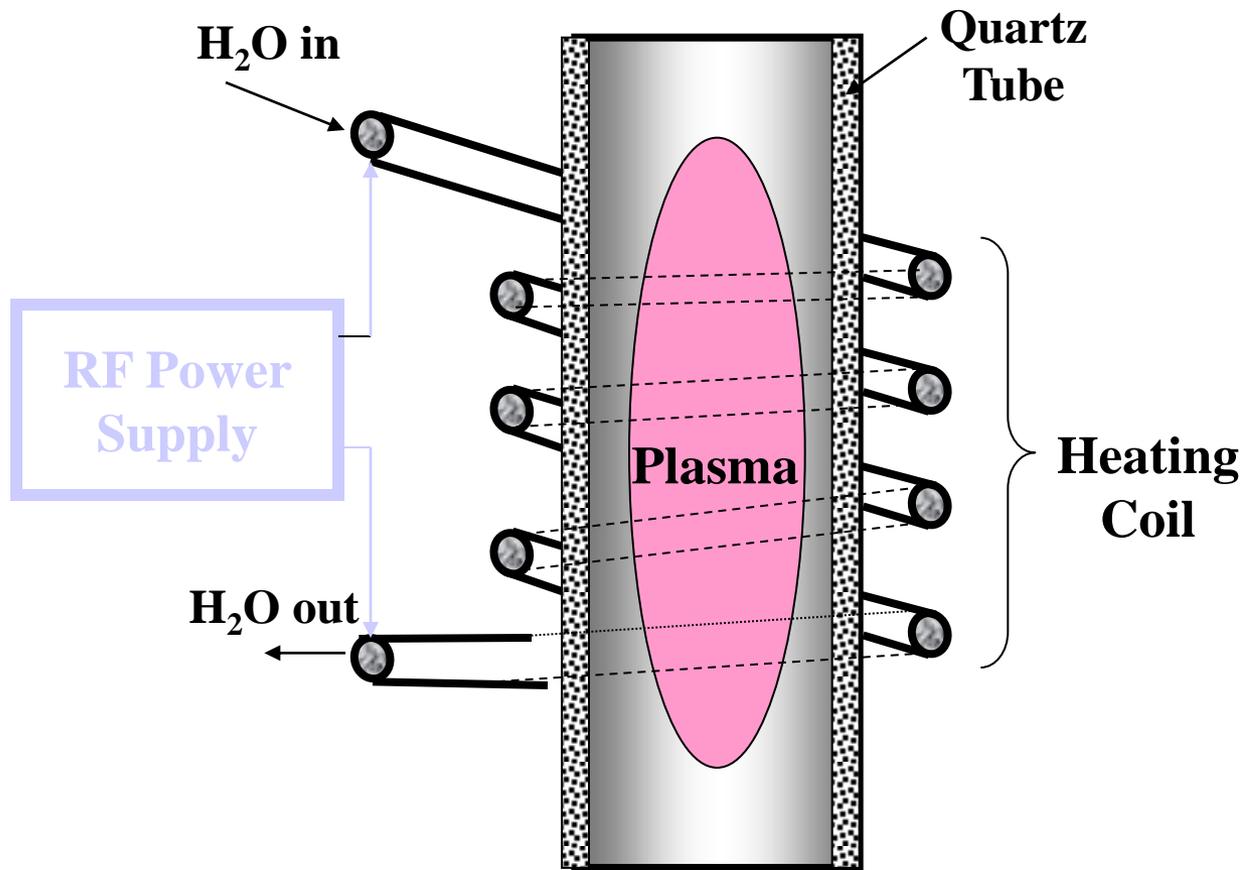
**Capacitive Coupling**

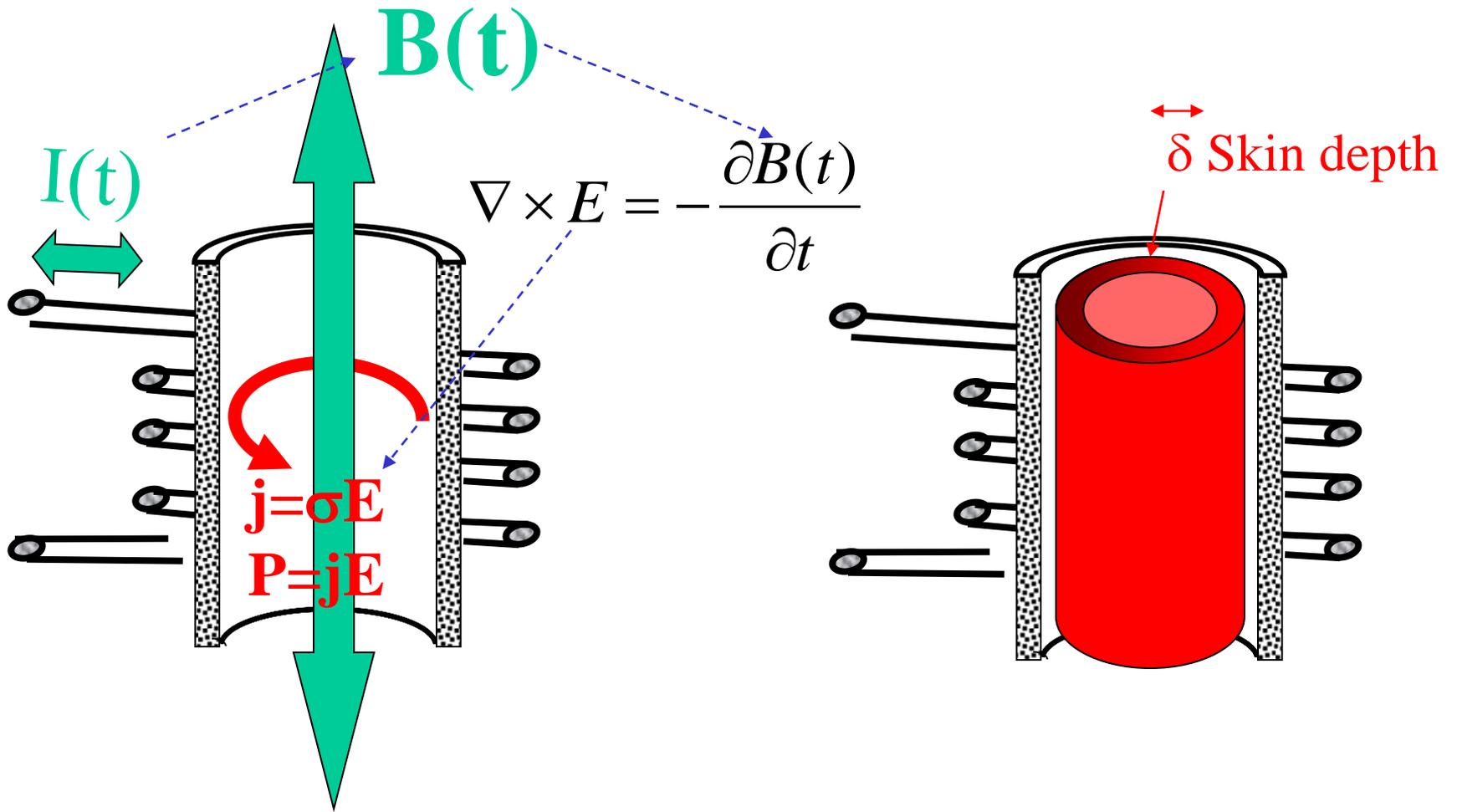
# Special Types of RF Discharges

[W/cm<sup>3</sup>]

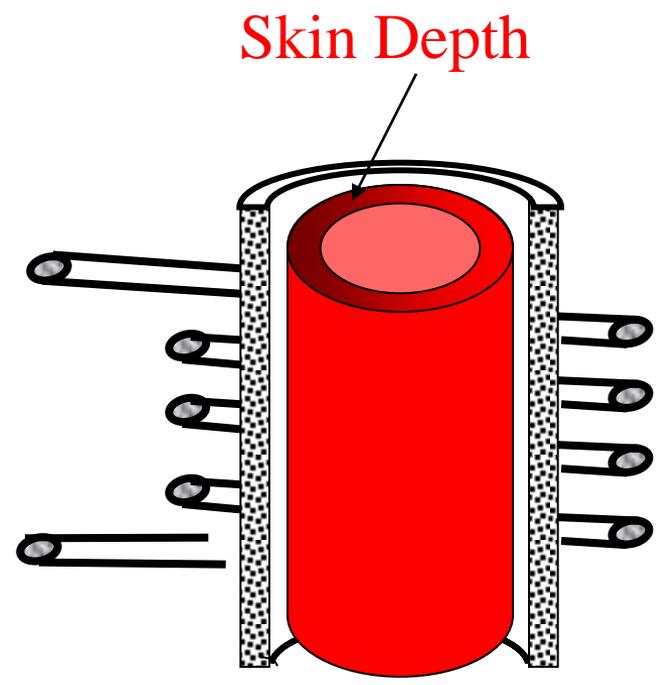
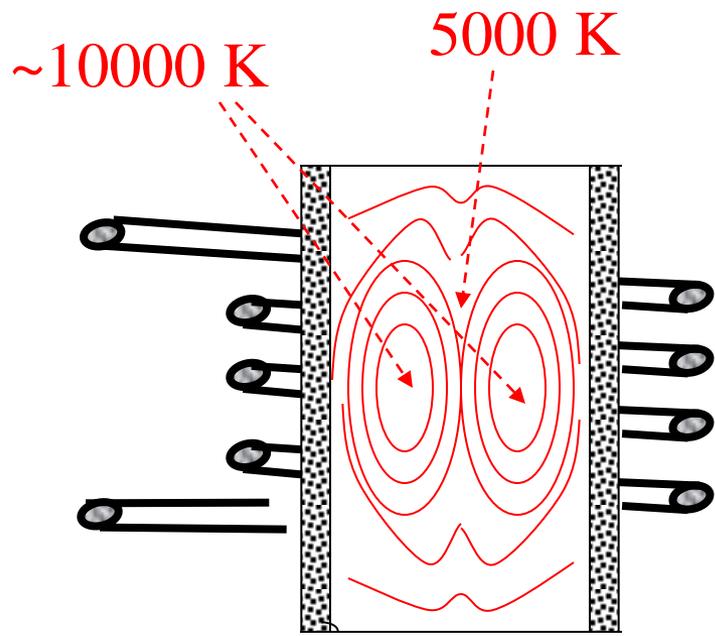


# RF Inductive Plasmas

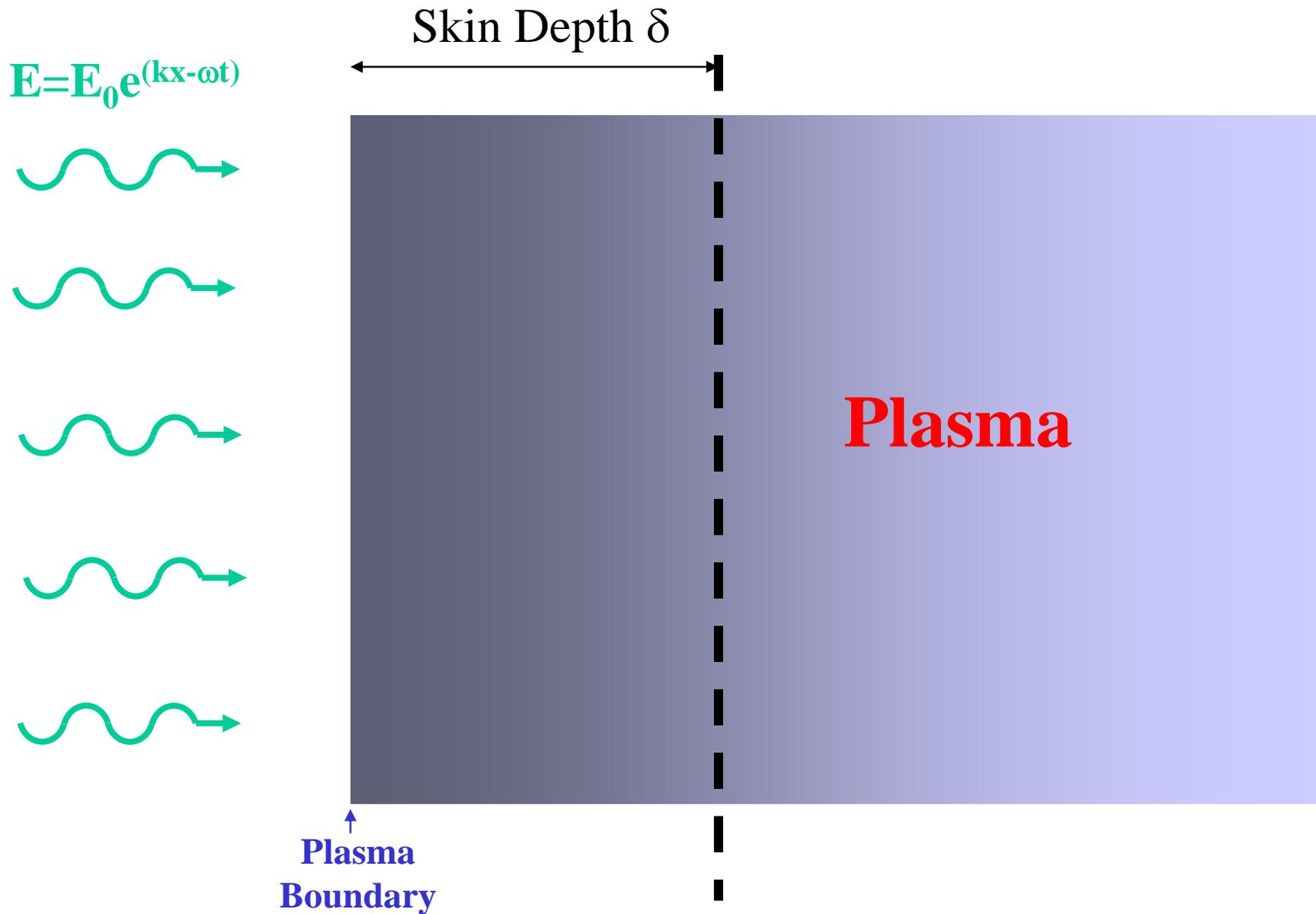




RF Discharge



# EM Wave Plasma Interaction



# Background I

## Maxwell's Equations

$$D = \epsilon_0 E + \cancel{P}$$

$$B = \mu_0 (H + \cancel{M})$$



$$\nabla \cdot D = \rho$$

$$\nabla \cdot B = 0$$

$$\nabla \times E = -\frac{\partial B}{\partial t}$$

$$\nabla \times H = j + \frac{\partial D}{\partial t}$$



$$\nabla \cdot E \approx 0$$

$$\nabla \cdot B = 0$$

$$\nabla \times E = -\frac{\partial B}{\partial t}$$

$$\nabla \times B = \mu_0 j + \mu_0 \epsilon_0 \frac{\partial E}{\partial t}$$

$\nabla \times$

$$j = \sigma E$$

$$\nabla \times (\nabla \times E) = \nabla(\nabla \cdot E) - \nabla^2 E \sim -\nabla^2 E$$

$$\nabla \times (\nabla \times E) = -\frac{\partial}{\partial t} (\nabla \times B)$$



$$\nabla^2 E = \mu_0 \sigma \frac{\partial E}{\partial t} + \mu_0 \epsilon_0 \frac{\partial^2 E}{\partial t^2}$$

$$\nabla^2 E = \mu_0 \sigma \frac{\partial E}{\partial t} + \mu_0 \epsilon_0 \frac{\partial^2 E}{\partial t^2}$$

$$E = E_0 e^{i(kx - \omega t)}$$

One Dimensional

$$\frac{\partial^2 E}{\partial x^2} - \mu_0 \sigma \frac{\partial E}{\partial t} - \mu_0 \epsilon_0 \frac{\partial^2 E}{\partial t^2} = 0$$

$$(k^2 + i\omega\mu_0\sigma + \mu_0\epsilon_0\omega^2)E = 0$$

$$c = \sqrt{\frac{1}{\epsilon_0\mu_0}}$$

$$k^2 = \left(\alpha + \frac{i}{\delta}\right)^2 = \frac{\omega^2}{c^2} + i \frac{\omega\sigma}{c^2\epsilon_0}$$

$$k = \underbrace{\sqrt{\frac{\sigma\mu_0\omega}{2} \left[ \frac{\omega\epsilon_0}{\sigma} - \sqrt{1 + \left(\frac{\omega\epsilon_0}{\sigma}\right)^2} \right]^{1/2}}}_{\text{Oscillation of EM field}} + i \underbrace{\sqrt{\frac{\sigma\mu_0\omega}{2} \left[ \sqrt{1 + \left(\frac{\omega\epsilon_0}{\sigma}\right)^2} - \frac{\omega\epsilon_0}{\sigma} \right]^{1/2}}}_{\text{Damping of EM in surface layer; } \left( = \frac{1}{\delta} \right)}$$

Oscillation of EM field

Damping of EM in surface layer;  $\left( = \frac{1}{\delta} \right)$

# Skin Depth

$$k = \sqrt{\frac{\sigma\mu_0\omega}{2}} \left[ \frac{\omega\epsilon_0}{\sigma} - \sqrt{1 + \left(\frac{\omega\epsilon_0}{\sigma}\right)^2} \right]^{1/2} + i \sqrt{\frac{\sigma\mu_0\omega}{2}} \left[ \sqrt{1 + \left(\frac{\omega\epsilon_0}{\sigma}\right)^2} - \frac{\omega\epsilon_0}{\sigma} \right]^{1/2}$$


Damping of EM in surface layer;  $\left( = \frac{1}{\delta} \right)$

$$\left\{ \begin{array}{l} \frac{\omega\epsilon_0}{\sigma} \ll 1 \quad \text{In most Industrial Plasmas} \\ \sigma = \frac{e^2 n_e}{m_e \nu_c} = \frac{\epsilon_0 \omega_p^2}{\nu_c} \quad \text{Electrical Conductivity} \end{array} \right.$$



$$\delta = 3 \times 10^6 \sqrt{\frac{\nu_{collision}}{n_e \nu_{Power}}} \quad (m)$$

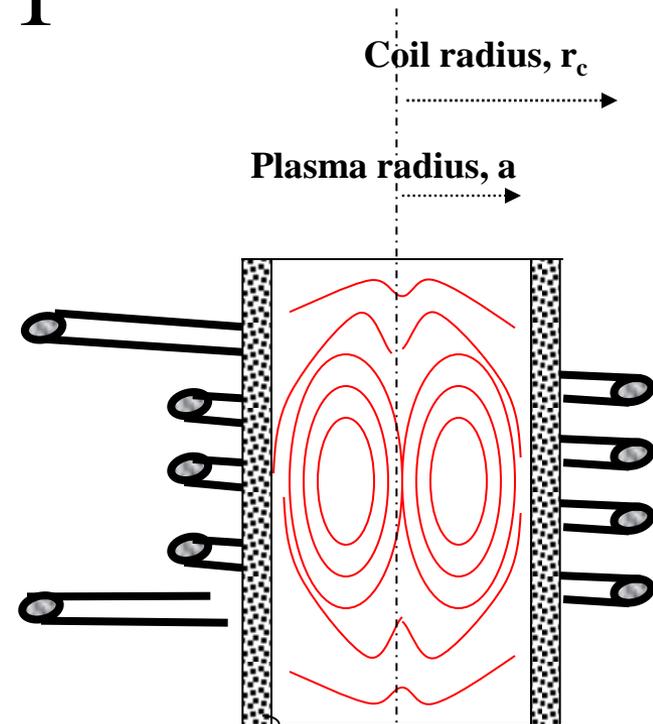
## Energy Coupling Parameter $\eta_c$

$$\left( \eta_c = \frac{\text{Discharge Power}}{\text{Reactive Power}} \right)$$

$$0 \leq \eta_c \leq 1$$

$$\eta_c \equiv f \left( \frac{a}{r_c}, \kappa \right)$$

Coupling parameter  $\kappa \equiv \sqrt{2} \frac{a}{\delta}$



Maximum power transfer: when skin depth ( $\delta$ ) is between 1/3 and 2/3 of the plasma radius or  $\kappa$  is between approximately 2 to 4.

# Background II

$$V_{Power}$$

$$V_{Plasma} = 8.98 \sqrt{n_e} \quad \leftarrow 1/m^3$$

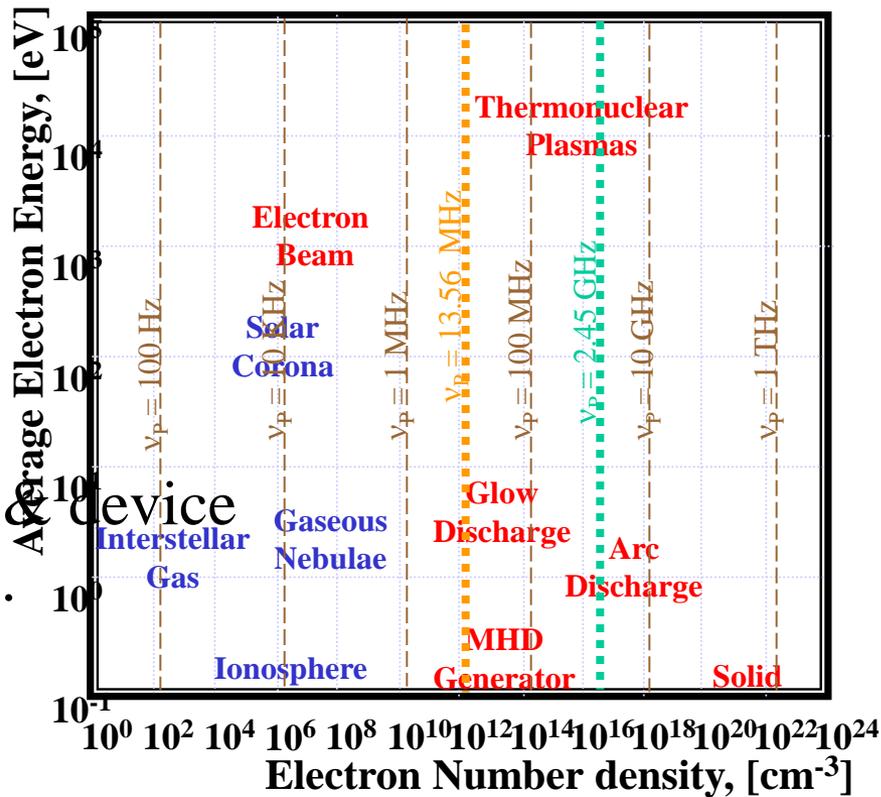
$$V_{gyro} = 2.8 \times 10^{10} B \quad \leftarrow \text{Tesla}$$

$$V_{collision} = 2.8 \times 10^{-8} \times \frac{n_e}{\sigma_{cond}}$$

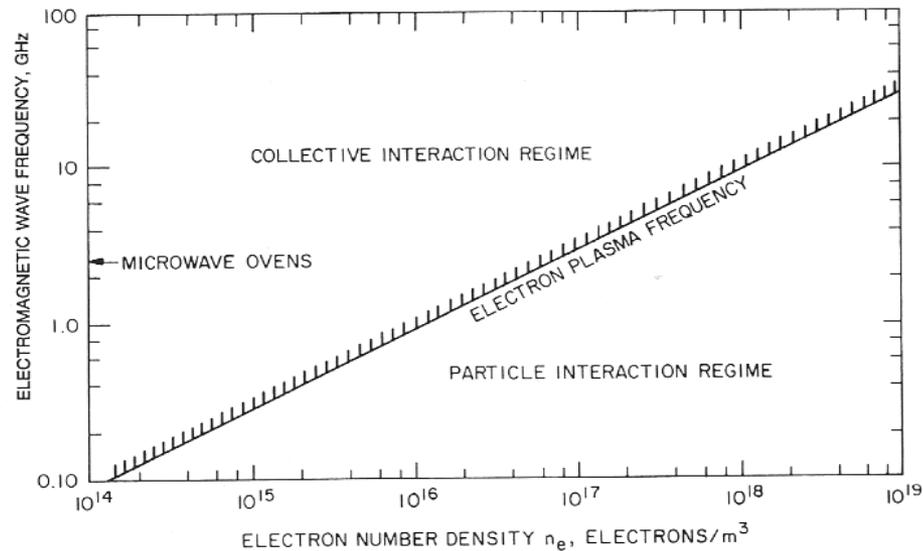
Plasma properties & device properties missing.

Energy transfer frequency ( $p = \sigma E^2 = \frac{\epsilon_0 \epsilon_r E^2 V}{2}$ )

$$V^* = \frac{8\pi^2 V_{Plasma}^2}{V_{collision}} = \frac{2\sigma_0}{\epsilon_0}$$



## INDUCTIVE RF ELECTRICAL DISCHARGES IN GASES



The electron plasma frequency, in gigahertz, as a function of the electron number density in electrons per cubic meter. In the particle interaction regime, below the electron plasma frequency, individual electrons can respond to the electric field of the electromagnetic wave; above the electron plasma frequency, the inertia of the individual electrons causes them to respond collectively.

### Particle interaction Regime

**(Absorption or Reflection)**

$$V_{Power} < V_{Plasma}$$

Magnetized  
Plasma

$$V_{gyro} < V_{Plasma}$$

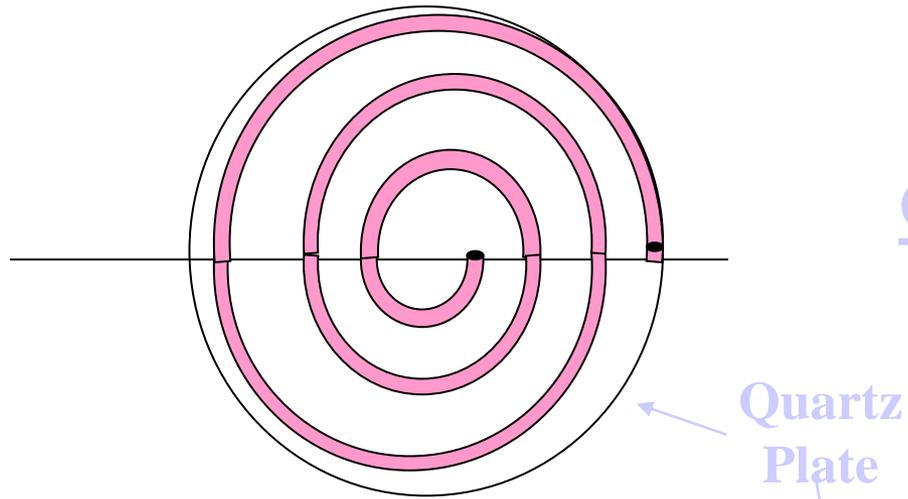
### Collective Interaction Regime

**(Interaction weak)**

$$V_{Power} > V_{Plasma}$$

$$V_{gyro} > V_{Plasma}$$

# GEC Reference Cell



Quartz Plate

